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Recent Advances in Optical Metrology

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Message from the Guest Editors

Dear Colleagues,

With the advances in scientific and technological development, optical metrology has been widely applied in applications such as industrial inspection, biomedical imaging, experimental mechanics, smart agriculture, and consumer entertainment. Based on the hardware devices and working principles. metrology can be divided into numerous different types: interferometry. structure light. laser holographic interferometry, digital holography, stereo vision, time of flight, etc. In recent years, many scholars have developed various advanced techniques for optical metrology and applied these advanced techniques into new application scenarios. This Special Issue focuses on, but is not limited to, the most up-to-date optical metrology and their applications.

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